

02-16-05

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**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application No. 10/720,724  
Filing Date: November 24, 2003  
Applicant: Mitsuro ATOBE  
Group Art Unit: 1763  
Examiner: Rakesh K. Dhingra  
Title: MASK VAPOR DEPOSITION METHOD, MASK VAPOR DEPOSITION SYSTEM, MASK, PROCESS FOR MANUFACTURING MASK, APPARATUS FOR MANUFACTURING DISPLAY PANEL, DISPLAY PANEL, AND ELECTRONIC DEVICE  
Attorney Docket: 9319K-000606

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

**AMENDMENT**

Sir:

In response to the Office Action mailed November 16, 2005, please amend the application as follows and consider the remarks set forth below.

**Amendments to the Abstract** begin on page 2 of this paper.

**Amendments to the Claims** begin on page 3 of this paper.

**Amendments to the Drawings** begin on page 5 of this paper.

**Remarks** begin on page 6 of this paper.